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TABLETOP SEM The Ultimate Solution

Microscopy





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SEC Co., Ltd. has been developing and selling equipment for inspection and analysis for over 20 years. Since our establishment in 1991, we have been continually developing the highest quality e-beam inspection equipment in Korea.

With the ability to locally source all components and constantly developing new technologies, SEC has distinguished itself amongst the global competition. With the ability to adapt to changes in technology, SEC offers products that can satisfy the customers needs.

E - beam pioneer

Specialized corporation in E-beam technology, leading the nano era

· 2017 ~

Launch of new models with lower price and ease-of-use functions

2012 ~ 2016

High resolution SNE-4500M (2012) Attains total sales of 500 SEM Systems & 1,000 X-ray Inspection System(2016)

2009 ~ 2012

100 Total Units sold (2009) Wins of Excellence Award at Innovative Technology Fair

- 2006~ Developed Tabletop-SEM
- 2000 ~ 2005 Developed X-ray Inspection System
- 1991 ~ 1999

SEC Engineering Establishe

"Speedy Entertaining Microscope"

With over 600units sold since its introduction in 2006, the Tabletop-SEM's developed by SEC offer the capabilities of the full size SEM in compact form. With its ease of use, even a novice SEM user can obtain high quality data with minimal training.

Superior Service & Exciting Challenge! Seeking the Best! Walking the right Path! Keeping the Faith!



10 billion **Dollars Awarded**

Tower of Export

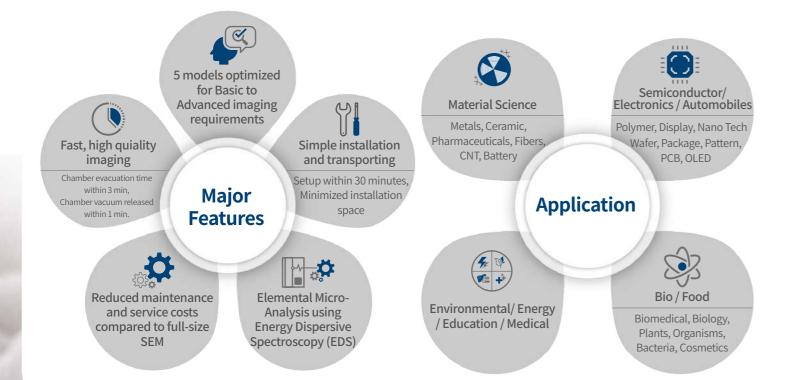
History



SCANNING ELECTRON MICROSCOPY -



What is Tabletop-SEM?



Performance

Model	SNE-4500M Plus(A)	SNE-4500M Plus(B)	SNE-4500M	SNE-3000MS	SNE-3200M
Resolution		5nm		15	inm
Magnification	150	,000x	100,000x	60,0	200x
Detector	SE	SE/BSE	SI	E	SE/BSE
Vacuum	High	High/Low	Hig	gh	High/Low
Stage	X, Y, R, Z, T : F	ully Motorized	X, Y, R, Z, T : Manual	X, Y, R :	Manual
Specification	ns				
Stage Traverse	X,Y :40mm R :360°	Z : 0 ~ 40mm T : -45 ~ 90°	X,Y :40mm R :360° T :0~45° Z :0~35mm	X, Y : 35mm	R : 360°
Max. Sample Size	80mm(D)	/ 50mm(H)	80mm(D) / 35mm(H)	70mm(D) /	/30mm(H)
CCD Camera	Top-View C	CCD Camera	-	-	
O.L Aperture Type	30	, 50, 50, 100μm(Variable Typ	pe)	200µm(Single)
Electron Beam Source		Pre-cent	tered Tungsten Filament C	artridge	
Acceleration Voltage	1kV ~		30kV (1/ 5/ 10/ 15/ 20/ 30) -	6 Step	
Display Mode		320 x 240 / 640 x 48	80 / 1.280 x 960 / 2.560 x 1.	920 / 5.120 x 3.840	

Model	SNE-4500M Plus(A)	SNE-4500M Plus(B)	SNE-4500M	SNE-3000MS	SNE-3200M
Resolution		5nm		15r	ım
Magnification	150	,000x	100,000x	60,0	00x
Detector	SE SE/BSE		SE		SE/BSE
Vacuum	High	High/Low	Hig	gh	High/Low
Stage	X, Y, R, Z, T : F	X, Y, R, Z, T : Fully Motorized		X, Y, R :	Manual
Specification	IS				
Stage Traverse	X,Y :40mm R :360°	Z : 0 ~ 40mm T : -45 ~ 90°	X,Y:40mm R:360° T:0~45° Z:0~35mm	X,Y :35mm	R :360°
Max. Sample Size	80mm(D) / 50mm(H)		80mm(D) / 35mm(H)	70mm(D) / 30mm(H)	
CCD Camera	Top-View CCD Camera		-	-	
O.L Aperture Type	30	, 50, 50, 100μm(Variable Typ	pe)	200µm(S	ingle)
Electron Beam Source		Pre-cen	tered Tungsten Filament C	artridge	
Acceleration Voltage	1kV ~ 30kV (1/ 5/ 10/ 15/ 20/ 30) - 6 Step				
Display Mode	320 x 240 / 640 x 480 / 1,280 x 960 / 2,560 x 1,920 / 5,120 x 3,840				
Automation Function	Start, Focus, Stigmator, Contrast & Brightness				
Image Format	BMP, JPEG, PNG, TIFF				
Vacuum Pump		Rotary + Turbo N	Aolecular Pump (Fully Auto	omation System)	



SNE-4500M Plus



SNE-4500M Plus model provides ease-of-use and the best performance of all.

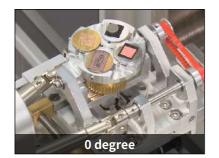
Fast moving by fully motorized stage and easy to find sample analyzing location with Top-view CCD camera.

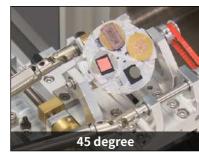
SNE-4500M has magnification of Maximum 150,000x, and it is optimized to surface / cross section analysis with the wide stage composition.

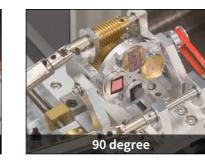
A Type : SE detector and high vacuum

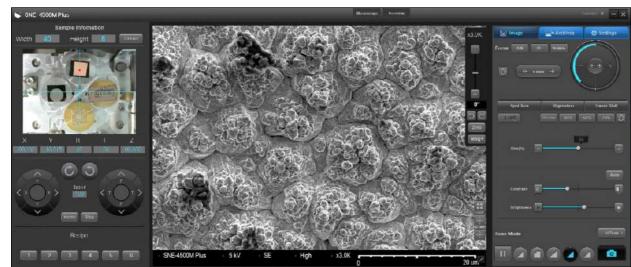
B Type : SE & BSE detector and high & low vacuum

"Tilting -45 to 90° degree"









Navigation Camera mode

Sample Images Snap Shot : Image saving function / Image rotates with Rotation.

Stage Control Mode

X, Y, R, Z, T - 5-axis Moving, Motor Speed Control, Move to Home, Anti-collision function.

Recipe Function

Save location(up to 6) and recall \rightarrow re-analyze the same location Able to save SEM analysis conditions and re-analysis in the same condition.

SNE-4500M



SNE-3200M



metal coating.

SNE-3000MS



The most economical model with optimized spectifications for easy SEM imaging. Able to image samples within 3 minutes from exchanging samples. Optional EDS is available also at entry level prices for precise elemental micro-analysis.

High Resolution Tabletop-SEM

The high resolving power allows real-time specimen inspection up to 100,000x. Obtaining high quality images of extremely small features or particles is made possible by utilizing the standard Variable Aperture(30, 50, 100µm) and optimal sample positioning with omnidirectional control of 5 axis stage.

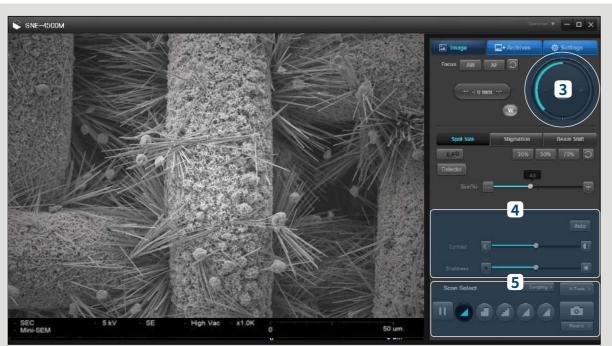
Advanced Tabletop-SEM

Both SE and BSE Detectors are included for SEM image analysis to enable diverse analysis for a wide variety of sample types. Both High and Low(charge reduction) Vacuum modes are standard allowing nonconductive sample analysis without

Entry-level Tabletop-SEM

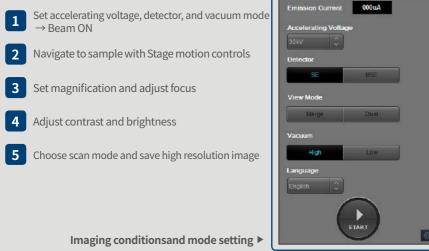
Main Features

SEM UI –



User centric software interface provides an easy-to-learn and conveniently organized interface.

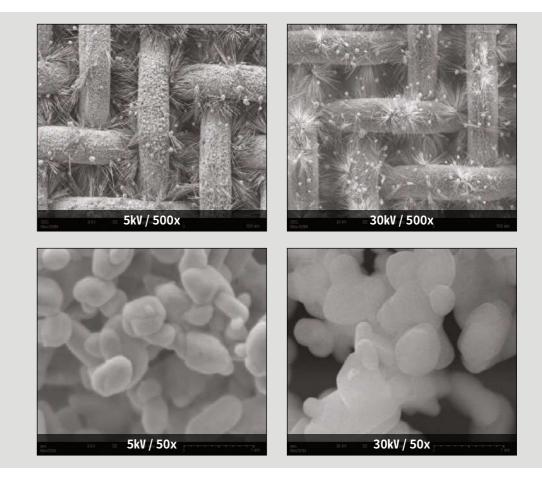
Easy Operating Procedures





Wide Range of Accelerating Voltages

With 1 ~ 30kV accelerating voltages, it is capable to get various images suitable for each sample's condition. (1/5/10/15/20/30kV)



Additional Functions





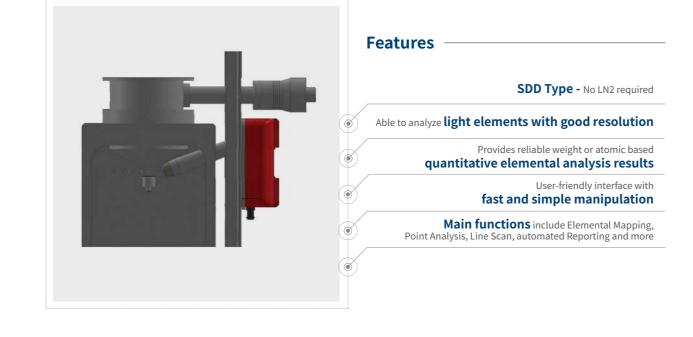
3 GUI is offering the measurement tools for size, angle and extent of the sample and edits tools for the brightness and contrast of saved images.

Shortcut key commands support more precise and rapid SEM imaging.

5 It is capable to operate image analysis and measurement tool programs such as 3D-view, Auto Count and Colorization by Image analyzer.

EDS

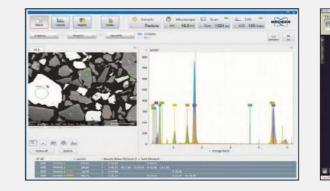
Energy Dispersive Spectroscopy(EDS) is optionally for analyzing sample composition. EDS is used for qualitative and quantitative elemental analysis by detecting characteristic X-rays generated as a result of the electron beam excitation of the atmic structure. EDS Detectors can be installed on all SEC SEM models and are available with both compact, simplified EDS software or more advanced spectroscopy solutions, all from well known industry standard EDS suppliers.



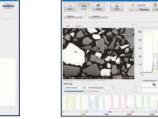
Specifications

Model	X Flash Series	Element
Brand		
Detector Type	Silicon Drift Detector (SDD)	Ultra-thin Silicon Nitride (Si₃N₄) Window
Energy Resolution	Mn ka :	≤ 129 eV
Detector Active Area	30mÅ	25m²
Detection Range	Boron(5) ~ A	mericium(95)
X-ray Throughput	> 150,000 cps	> 100,000 cps

EDS Software



Line Scan



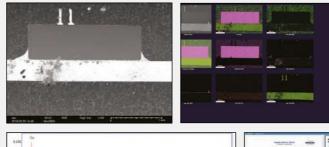
Acquire fast and accurate qualitative or quantitative analysis results with automatic peak deconvolution providing higher accuracy and reliable results for the defined area or point of interest.

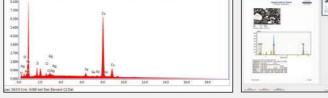
Qualitative or Quantitative Analysis

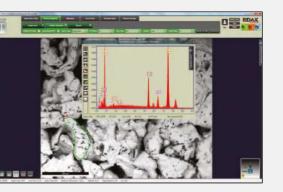
The line scan mode provides comparative elemental analysis along a user defined line with element profiles graphically representesd. Great for cross section thickness and elemental transition mizing studies.

Report

Available for variable report formats and editable with desired formats.

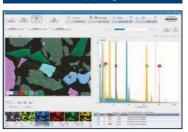








Mapping

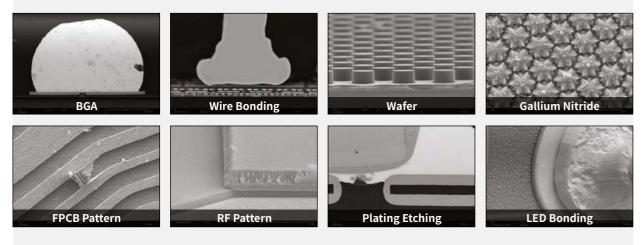


Produce colorized maps with colorcoded elemental distributions to represent to all the elements present and where they are located within an area of the specimen.

-	Element	Weight	Atomic %	Net Int.	Error %
	0	1.54	5.66	68.23	11.83
	Si	2.62	5.50	152.87	9.59
1	CI	0.52	0.86	41.08	15.79
1	Ag	1.97	1.08	85.82	10.24
	Fe	2.18	2.30	114.16	8.88
	Ni	1.33	1.34	43.87	13.53
	Cu	89.83	83.27	2061.44	2.20

SEM Application & Image

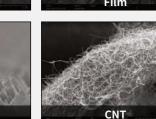
Semiconductor & Electronics



Energy & Chemistry



Solar Cell



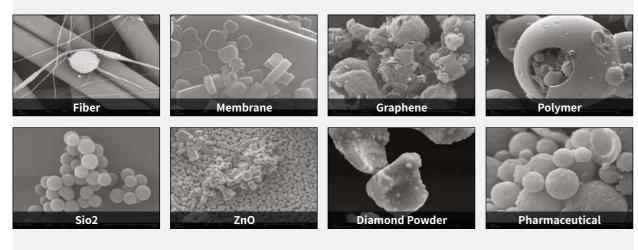




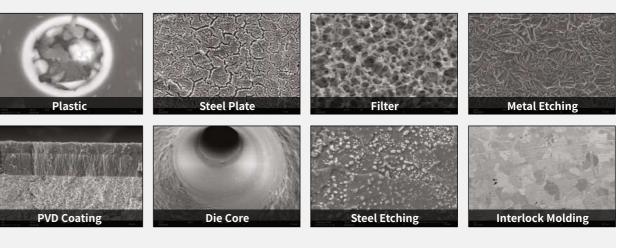




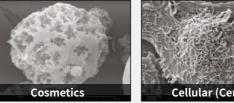
Materials

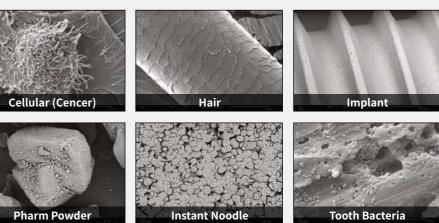


Automotive & Metals



Medical & Health

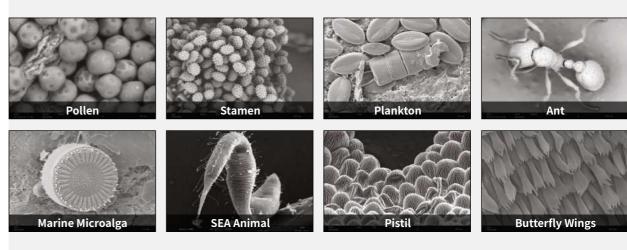








BIO



COMPARISON (SE / BSE Image)

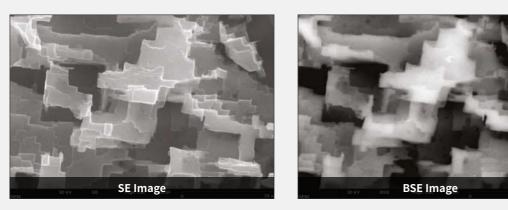
SE - Secondary Electron

Provieds images with surface topography depicted in fine detail.

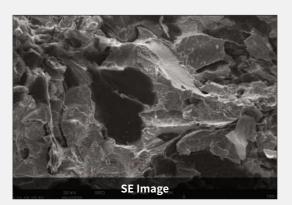
BSE - Back Scattered Electron

Provides images with atomic weight contrast as brighness follows the elemental atomic number.

Smartphone Metal Case

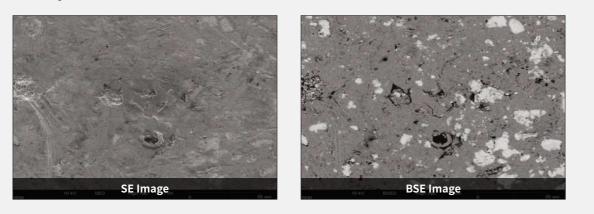


Ceramic





Metal Alloy

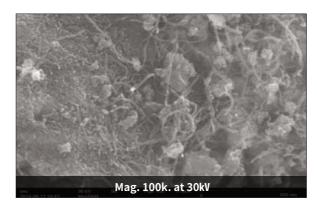


High Resolution Performance

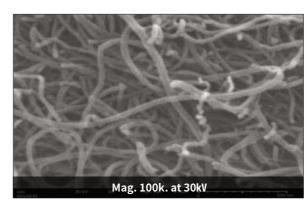
SEC's SEM models provide "live" imaging up to 150,000x. It is offering the high-level resolution image among Tabletop-SEM models and it is able to get the optimal images for sample's features by accelerating voltage.

Lanthanum Powder

C



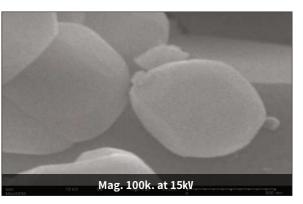
Carbon Nano Tube



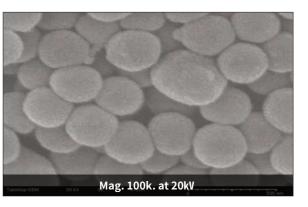
Battery —



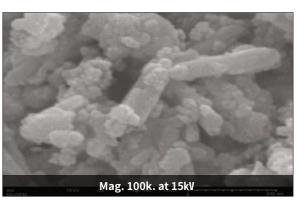
Ceramic



TiO2



Emulsion



OPTION

Ion Sputter Coater



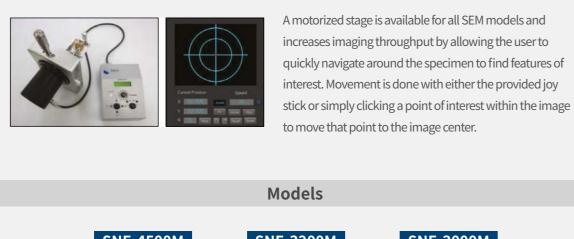
The Ion Sputter Coater allows for imaging of nonconductive samples in high vacuum mode for the highest resolution imaging. Sputter coaters increase conductivity by coating the test specimen with a few nanometer thick metal film of Au or Pt. The higher conductivity increases the amount of secondary electron generation and creates higher resolution images.

Coating Target Au or Pt

MCM-100P Quick Mode

MCM-200 Touch PAD - Advanced Mode

Motorized Stage



SNE-4500M



SNE-3000M

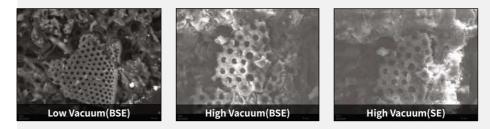




Using both SE and BSE detectors, the software allows creating composite images that reveal both topographic and composition combined into a single image - able to get 3-dimensional image.

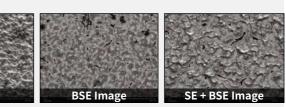
4-Channel Solid State Type : 4 segment Silicon Diode

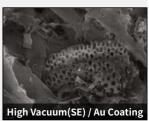
Low Vacuum Mode



Analysis non-conductive samples - NO conductive coating required.

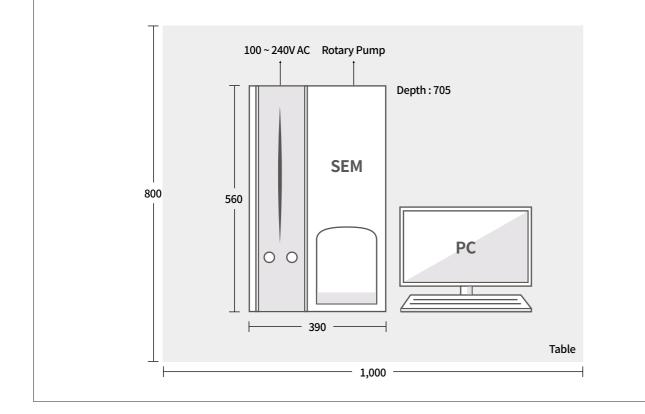
Charge-Up Reduction Mode(BSED + Low Vacuum)





SEM Spec Overview

Example of Installation Layout



Control System	
OS	Microsoft Window®7 or 10
CPU	Intel [®] Core™ 15
Memory / HDD	4GB / 500G
Interface Connector	USB 2.0
Monitor	22 inch Wide

Dimensions and Weight		
Main Unit	390(W) x 380(D) x 560(H), 88kg	
Controller Unit	390(W) x 325(D) x 560(H), 30kg	
Rotary Pump	400(W) x 160(D) x 340(H), 24kg	

Installation Condition		
Temperature	15 to 30°C	
Humidity	Less than 80%	
Power Source	Single Phase AC 100 ~ 240V 1kW, 50 / 60Hz	

Dimensions and Weight

Tungsten Filament(Pre-centered cartridge assembly)
Sample Holders / Stubs(15 & 25mm dia, 0/ 45/ 90 Tilt)
Carbon Tape
Blower
Storage BOX
Vacuum Grease
Pincette
Working Distance Jig
Tools and Wrenches
Operation Manual & CD

Standard Items Included
SEM Unit
Pump Unit(Rotary + Turbo)
PC(Desktop PC)
Monitor

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